

Docket No. 56775 (70551)

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANT:

N. Kanetsuki, et al.

EXAMINER: L. Vinh

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Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

## **RESPONSE TO OFFICE ACTION**

The following is in response to the Office Action mailed February 21, 2003, in the above referenced application.

18/4/03